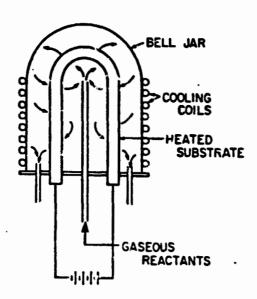
SILICON PRODUCTION IN AN AEROSOL REACTOR

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Siemens Process



Silane Pyrolysis

$$SiH_4 + M \xrightarrow{1} SiH_2 + H_2 + M$$

$$SiH_2 + SiH_4 \stackrel{?}{=} Si_2H_6 \xrightarrow{3} Si_2H_4 + H_2$$

$$SiH_2 - Si_2H_6 \stackrel{4}{=} Si_3H_8 \stackrel{5}{=} Si_2H_4 + SiH_4$$

$$SiH_2 \stackrel{6}{-} surface - SiH_2$$

$$surface - SiH_2 + SiH_4 \xrightarrow{7} surface - SiH_3 + SiH_3$$

$$SiH_3 + SiH_3 \xrightarrow{8} Si_2H_6$$

SILICON MATERIAL

Aerosol Reactor

- Efficiency energy & reactant usage
- Product purity
- Continuous rather than batch process
- Product particle size $D > 10-50~\mu m$ to facilitate separation and subsequent processing

Simultaneous Nucleation and Particle Growth

$$\rho_g \, \frac{\partial n(a,t)/\rho_g}{\partial t} + \rho_g \, \, \frac{\partial}{\partial a} [\dot{a}n(a,t)/\rho_g] = J_c \, \delta(a-a^*)$$

$$\rho_g \frac{\partial C_{v/} \rho_g}{\partial t} = -C_p \int_{a^*}^{\infty} 4\pi a^2 n(a,t) \dot{a} da - C_p \frac{4}{3} \pi a^{*3} J_c + R$$

Traditional approach:

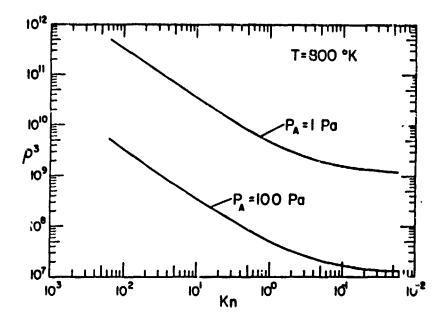
$$J_c = J(\overline{c_v})$$

Clearance Volume approach:

$$J_c = \begin{cases} J(c_{v\infty}) \cdot (1 - \Omega) & 0 \le \Omega \le 1 \\ 0 & \Omega > 1 \end{cases}$$

where

$$\Omega = \int_{0}^{\infty} \frac{4}{3} \pi a^{3} \rho^{3} n(a,t) da$$



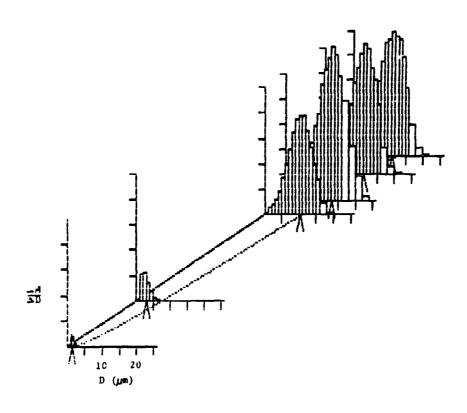
Aerosol Reactor for Growth of Large Silicon Particles by Silane Pyrolysis

- 1. Generate seed particles by pyrolysis of a small amount of silane.
- 2. Mix seed aerosol with primary silane flow, limiting number concentration such that the amount of silane is sufficient to grow the desired size of particles from the seed.
- 3 React the silane at a rate which is controlled such that the seed particles scavenge the condensible vapors rapidly enough to inhibit further nucleation.

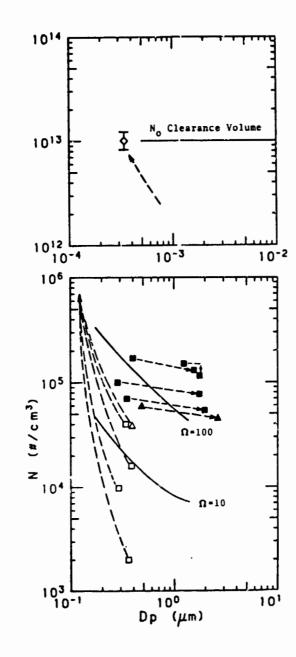
Reactor Optimization

- Control rate of condensible vapor production by limiting rate of temperature increase.
- Maintain $\Omega > \Omega$ * to prevent nucleation.
- Ω depends on particle size and concentration so the growth history is important.
- Integrate rate equations to evaluate $\Omega(t)$. Adjust T(t) to satisfy $\Omega_{\min} > \Omega^*$ at all times.
- Use high temperature burn-off to guarantee complete reaction.

WHAT IS THE APPROPRIATE VALUE FOR $\Omega *$?



SILICON MATERIAL





SILICON MATERIAL

Conclusion^c

- Particles of low volatility materials can be grown to large size in aerosol leactors by controlling the reaction rates to minimize nucleation.
- The clearance volume model provides reasonable estimates of suitable operating conditions.
- The "total clearance volume fraction" must be large (order 20-40) to quench nucleation.
 - Nucleation quenching by a growing aerosol is extremely sensitive to seed particle size.